Application/Control Number: 10/647,329

Art Unit: 1763

## DETAILED ACTION

## Allowable Subject Matter

Claims 15-26 are allowed.

The following is an examiner's statement of reason for allowance: a plasma CVD apparatus including a plasma confining electrode disposed between a first electrode and a second electrode to separate a plasma generation area; and gas supply and distribution hollow structure disposed between the plasma confining electrode and the second electrode, wherein the hollow structure having radical passage holes and neutral gas passage holes and having a plurality of gas diffusion plates, a total opening area of the neutral gas passage holes of the plurality of gas diffusion plates is smaller on a side of the upper plate than on a side of the lower plate of the hollow structure.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Parviz Hassanzadeh whose telephone number is (571)272-1435. The examiner can normally be reached on Tuesday-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Gregory Mills can be reached on (571)272-1439. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Parviz Hassanzadeh Primary Examiner Art Unit 1763

April 9, 2004